

RECEIVED
CENTRAL FAX CENTER

DEC 01 2003

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Jack O. Chu, et al.

Examiner: E.J. Kielin

Serial No.: 09/692,606

Art Unit: 2813

Filed: October 19, 2000

Docket: YOR920000344US1 (17178)

For: LAYER TRANSFER OF LOW DEFECT
SiGe USING AN ETCH-BACK PROCESS

Dated: December 1, 2003

Commissioner for Patents
Alexandria, VA 22313-1450**OFFICIAL****RESPONSE UNDER 37 C.F.R. § 1.111**

Sir:

In response to the Office Action dated July 31, 2003, applicants submit the following amendments and remarks for entry of record in the above-identified patent application.

CERTIFICATE OF MAILING UNDER 37 C.F.R. §1.8(a)

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Commissioner for Patents, Box 1450, Alexandria, VA 22313-1450 on December 1, 2003.

Dated: December 1, 2003


Susan Formicola